



PTO/SB/08A (10-01)

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## INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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Sheet

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of

6

### Complete if Known

Application Number	10/627,303
Filing Date	7/24/03
First Named Inventor	Patel
Art Unit	Not Yet Assigned
Examiner Name	Not Yet Assigned

Attorney Docket Number P109-US

### U.S. PATENT DOCUMENTS

Examiner Initials <sup>1</sup>	Cite No. <sup>1</sup>	Document Number Number- Kind Code <sup>2</sup> (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
BUT		US- 3,511,727	05-12-1970	Hays, R.G.	
		US- 4,190,488	02-26-1980	Winters, H.F.	
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BUT		US- 2003/0166342 A1	09/04/03	Chinn, et al.	

### FOREIGN PATENT DOCUMENTS

Examiner Initials <sup>1</sup>	Cite No. <sup>1</sup>	Foreign Patent Document Country Code <sup>3</sup> -Number <sup>4</sup> - Kind Code <sup>5</sup> (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T <sup>6</sup>
BUT		EP-0704884-A2	04-03-1996	Mehta, J.		
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BUT		WO-98/32163	07-23-1998	Tai et al.		

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Sheet 2 of 6

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		Number - Kind Code <sup>2</sup> (if known)			
BNJ		US- 6,409,876 B1	06-25-2002	McQuarrie, et al.	
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		Country Code <sup>3</sup> - Number <sup>4</sup> - Kind Code <sup>5</sup> (if known)				
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<b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b> <i>(use as many sheets as necessary)</i>				Application Number	10/627,303
				Filing Date	7/24/03
				First Named Inventor	Patel
				Art Unit	Not Yet Assigned
				Examiner Name	Not Yet Assigned
Sheet	3	of	6	Attorney Docket Number	

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**INFORMATION DISCLOSURE  
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Group Art Unit	Not Yet Assigned
Examiner Name	Not Yet Assigned

Attorney Docket Number

P109-US

**OTHER PRIOR ART – NON PATENT LITERATURE DOCUMENTS**

Examiner Initials <sup>1</sup>	Cite No. <sup>1</sup>	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T2
BNI		ALIEV et al., "Development of Si(100) Surface Roughness at the Initial Stage of Etching In F2 and XeF2 Gases Ellipsometric Study", Surface Science 442 (1999), pp. 206-214.	
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BUT		Kurt Williams, Etch Rates for Micromachining Processing-Part II, 2003 IEEE, Pgs 761-778, Journal of Microelectromechanical Systems, Vol. 12, No. 6, December 2003.	
		WINTERS et al., "The Etching of Silicon with XeF <sub>2</sub> Vapor", Appl. Phys. Letter, Vol. 34(1) (January 1, 1979), pp. 70-73.	
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